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COMMERCIAL SESSION

Todd Hastings, University of Kentucky

MENTORSHIP PROGRAM

Leonidas E. Ocola, Argonne National Laboratory

MEETING PLANNERS

Melissa Widerkehr, Wendy Walker, Widerkehr and Associates

PROGRAM COMMITTEE & SECTION HEADS

Directed Self Assembly

Joy Cheng, Elizabeth Dobisz, Euclid Moon, Paul Nealey, Martin Peckerar, Caroline Ross, Ricardo Ruiz, Hiroshi Yoshida

Electron or Ion Beam Lithography

John Hartley, Todd Hastings, Uli Hoffmann, Hans Loeschner, Juan Maldonado, John Melngailis, Steve Rishton, Don Tennant

Electron or Ion Sources and Systems

Alan Brodie, Nick Economou, Lloyd Harriott, Pieter Kruit, Juan Maldonado

Emerging Technologies

Charles Black, Mike Fritze, Cindy Hanson, Dieter Kern, Shinji Matsui, Paul Nealey, R. Fabian Pease, Martin Peckerar, John Randall, Hank Smith, David Tanenbaum, Grant Willson

Extreme UV Lithography

Uwe Behringer, Marty Feldman, Kenneth Goldberg, Eric Hendrickx, Patrick Naulleau, Takeo Watanabe

Maskless Lithography

Steve Brueck, David Joy, Juan Maldonado, Rajesh Menon, Dan Pickard, Mordechai Rothschild, Mark Schattenburg

Metrology, Imaging and Alignment

Eric Anderson, Leili Baghai Rad, Ralf Heilmann, David Joy, Euclid Moon, Phillip Russell

Nanobiology

Reginald Farrow, James Grote, Francis Ligler, Regina Luttge, Shalom Wind

Nanoelectronics

Karl Berggren, Andrew Dzurak, Peter Grutter, Stella Pang, Phil Wong, Qiangfei Xia

Nanoimprint and soft lithography

Steve Chou, Dan Kercher, Shinji Matsui, Deirdre Olynick, Stella Pang, Minghao Qi, Douglas Resnick, Helmut Schiff, Grant Willson

Nano-MEMS

Uwe Behringer, Richard Blaikie, Rebecca Cheung, Julia Greer, Leonidas E. Ocola

Nanophotonics and Plasmonics

Richard Blaikie, Steven Brueck, Mark Horn, Alex Little, Rajesh Menon, Daniel Pickard

Nanostructures and Pattern Transfer

Evangelos Gogolides, Ralf Heilmann, Mark Horn, Derrick Mancini, Raghunath Murali, Deirdre Olynick, Stella Pang, Minghao Qi, Richard Tiberio, Joel Wendt

Optical Lithography

Steve Brueck, Tim Brunner, Michael Fritze, Tim Groves, Shinji Okazaki, Shane Palmer, Mordechai Rothschild, Henry Smith, Bruce Smith

Patterned Media and Data Storage

S. Assefa, Elizabeth Dobisz, Kim Lee, Caroline Ross, Shuaigang Xiao

Resists

Karl Berggren, R Brainard, Theodore Fedynyshyn, Frances Houle, Chris Soles, Gregory Wallraff

Simulation and Modelling

Tim Brunner, Roxann Engelstad, Chris Mack, David Melville, Lawrence Melvin, Martin Peckerar, Frank Schellenberg, Kevin Turner

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Evangelos Gogolides
Timothy Groves
Peter Grutter
Cornelis (Kees) Hagen
Cynthia Hanson
Ralf Heilmann
Eric Hendrickx
Ulrich Hofmann
Charles Holzwarth
Walter Hu
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